



PATENT APPLICATION

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In re the Application of

Masashi UEDA et al.

Application No.: 09/830,879

Docket No.: 109426

Filed: May 2, 2001

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SEP 14 2001

TC 1700

For: INTERNAL ELECTRODE TYPE PLASMA PROCESSING APPARATUS AND  
PLASMA PROCESSING METHOD

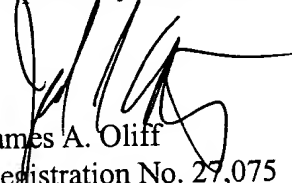
REQUEST FOR CORRECTION OF PALM RECORDS

Director of the U.S. Patent and Trademark Office  
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Sir:

Attached is a photocopy of the original filing receipt on which errors have been corrected in red. These errors are being brought to the attention of the Patent and Trademark Office so that it may correct its records.

Respectfully submitted,

  
James A. Oliff  
Registration No. 27,075

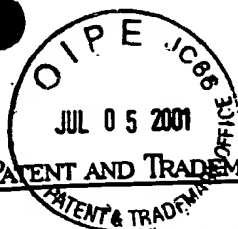
Joel S. Armstrong  
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Date: July 5, 2001

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APPLICATION NUMBER	FILING DATE	GRP ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLAIMS	IND CLAIMS
09/830,879	05/02/2001	1734	1100	109426	7	18	6

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 P O Box 19928  
 Alexandria, VA 22320


CONFIRMATION NO. 5332

FILING RECEIPT



\*OC00000006166169\*

Date Mailed: 06/08/2001

Receipt is acknowledged of this nonprovisional Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Customer Service Center. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

## Applicant(s)

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 Assignment for Published Patent Application  
 ANELVA CORPORATION

## Domestic Priority data as claimed by applicant

THIS APPLICATION IS A 371 OF PCT/JP00/06189 09/11/2000

## Foreign Applications

 JAPAN 11/255219 09/09/1999  
 JAPAN 2000/56584 03/02/2000

Projected Publication Date: N/A

Non-Publication Request: No

Early Publication Request: No

## Title

 Internal electrode type plasma  
 Inner-electrode-plasma processing apparatus and method of plasma processing method

Preliminary Class

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